DEPARTMENT OF METALLURGICAL AND MATERIALS ENGINEERING



NATIONAL INSTITUTE OF TECHNOLOGY TIRUCHIRAPPALLI-15

20-02-2013

## **Proceedings of Pre-bid Conference/Meeting**

Ref: NITT/F.No.0 55/PLAN2012-13/MME

Venue: Committee Room, MME Dept. NIT Trichy

## Name of the Equipment: Field Emission Scanning Electron Microscope with WDS and EBSD

S.N o	Reference in Tender Document	Query/Clarification sought	Clarification/Amendments make by NIT Trichy
1	4.c	Anti contamination trap is unique for one or two brands	Changed as "Suitable anti contamination technique for ensuring chamber cleanliness"
2	5.c	80 mm dia is more for air lock specimen chamber	Changed to "30 mm dia or more"
3	7.a	Mentioned crystals are unique for WDS	Changed to "WDS Should include suitable crystal to cover B-U elements (Be-U can be quoted as optional) along with required softwares, interface kit to integrate with FE-SEm along with calibration standards (min. 10mm stub). It should have provision for gate valve assembly. Pentane gas cylinder should also be provided."
4	9.g	Back up requirement is too high (10 hrs) which requires too much space and maintenance	Changed from 10hrs to 01hr
5	11.b	Suggested to have multiple sample polishing unit	Changed as "Branded multiple specimen electro polishing unit for EBSD sample preparation" – 1No.
6	11.d	Suggested to have lower window area with with LN2 or LN2 free	Changed to "10mm <sup>2</sup> instead of 30 mm <sup>2</sup> and it EDS should be LN2 free."
7	11	Suggested to have additional attachment "beam induced current mapping"	Additional point is added in section 11 as 11.e "Provision for beam induced current mapping"